# SERVICE CONSORTIUM, INC.

# OVERLAY DATA SHEET

Sheet No _____ of _____
System No. _____
Location _____

Reader _____ Mask S/N _____ View _____

Aligner _____ Exp _____

Temperature Settings
Mask Arm _____ Wafer Arm _____ Mask _____

| Wafer | 1 X | 1 Y | 2 X | 2 Y | 3 X | 3 Y | 4 X | 4 Y | 5 X | 5 Y | 6 X | 6 Y | 7 X | 7 Y | 8 X | 8 Y | 9 X | 9 Y | Y mag | X mag | θ |
|---|---|---|---|---|---|---|---|---|---|---|---|---|---|---|---|---|---|---|---|---|---|
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|---|---|---|
| Y-mag | $Y_1 - Y_5$ | Pos (+): increase environmental temp;<br>Neg (-): decrease environmental temp.<br><br>Each degree change = 3.6 μ inches. |
| X-mag | $X_9 - X_6$ | Lower left vernier (**C**)<br>Pos (+): CW adjustment;<br>Neg (-): CCW adjustment.<br>Each division = 5 μ inches. |
| θ | $Y_6 - Y_9 - X_1 + X_5$ | Lower right vernier (B)<br>Pos (+): CW adjustment;<br>Neg (-): CCW adjustment.<br>Each division = 5 μ inches. |

| Inverting Microscope | Non-inverting Microscope |
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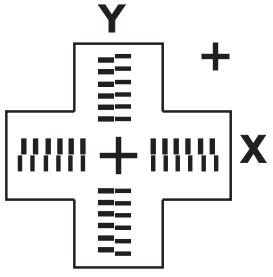
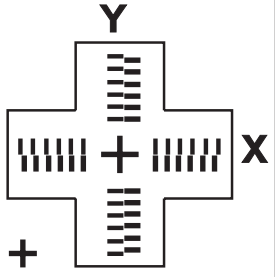
|  |  |





Service Consortium, Inc. • Microlithography Equipment Specialists • 1759 S Main St Su 100 • Milpitas, CA 95035 • (408) 935-9700 • Fax: (408) 719-9700 • www.servcon.com